
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Eib et al.

Attorney Docket No.:
03-1810/LSI1P239

Application No.: Not yet assigned

Examiner: Not yet assigned

Filed: Herewith

Group: Not yet assigned

Title: OPTIMIZED MIRROR DESIGN FOR
OPTICAL DIRECT WRITE

INFORMATION DISCLOSURE STATEMENT
37 CFR §§1.56 AND 1.97(b)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

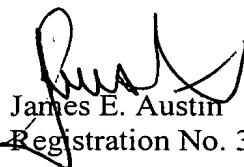
Dear Sir:

The references listed in the attached PTO Form 1449, copies of which are attached, may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is: (i) filed within three (3) months of the filing date of the above-referenced application, (ii) believed to be filed before the mailing date of a first Office Action on the merits, or (iii) believed to be filed before the mailing of a first Office Action after the filing of a Request for Continued Examination under §1.114. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 12-2252 (Order No. 03-1810).

Respectfully submitted,
BEYER WEAVER & THOMAS, LLP


James E. Austin
Registration No. 39,489

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| Form 1449 (Modified) | Atty Docket No. LSI1P239/03-1810 | Application No.: Not yet assigned |
| Information Disclosure Statement By Applicant | Applicant: Eib et al. | |
| (Use Several Sheets if Necessary) | Filing Date Herewith | Group Not yet assigned |

U.S. Patent Documents

Foreign Patent or Published Foreign Patent Application

Other Documents

| Examiner Initial | No. | Author, Title, Date, Place (e.g. Journal) of Publication |
|------------------|-----|--|
| | A1 | Shroff et al., "Optical Analysis of Mirror Based Pattern Generation", Emerging Lithographic Technologies VII, pp. 550-559. © 2003. |
| | | |
| | | |
| Examiner | | Date Considered |

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.